

Substitute form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

1

of

2

Complete if Known

Application Number

not yet assigned

10/796146

Filing Date

concurrently herewith

First Named Inventor

Daniel J.C. Herr

Group Art Unit

Examiner Name

Attorney Docket Number

5347-204CT

U.S. PATENTS AND PATENT PUBLICATIONS

Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
<i>lu</i>	1	US-3,582,176		Mathisen	06/1971
<i>lu</i>	2	US-4,325,637		Moore	04/1982
<i>lu</i>	3	US-4,498,771		Makosch et al;	02/1985
<i>lu</i>	4	US-4,614,427		Koizumi et al;	09/1986
<i>lu</i>	5	US-5,568,256		Koener et al; (Köner)	10/1996
<i>lu</i>	6	US-5,923,423		Sawatari et al;	07/1999
<i>lu</i>	7	US-5,455,850		Howells et al;	10/1995
<i>lu</i>	8	US-5,973,807		Buchkremer et al;	10/1999
		US-			
		US-			
		US-			

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T
		Office	Number	Kind Code (if known)			
<i>lu</i>	9.		11-329944		JPO (Abstract in English)	11/1999	
<i>lu</i>	10.		2221353		Great Britain	01/1990	
<i>lu</i>	11.		06-283585		Japan	10/1994	
<i>lu</i>	12.		03-295408		Japan	12/1991	
<i>lu</i>	13.		09-016062		Japan (Abstracts)	01/1997	

Examiner Signature


Date Considered

11/29/01

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Substitute form 1449A/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/7966110
		Filing Date	
		First Named Inventor	
		Group Art Unit	
		Examiner Name	
Sheet 2 of 2	Attorney Docket Number		

OTHER NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
u	14.	V. Georges et al; <i>Images charged objects using low-energy-electron coherent beams</i> , Ultramicroscopy 90 (2001) pp 32-38.	
u	15.	Palmer et al., "Diffraction gratings," Rep. Prog. Phys., Vol. 38, 1975, pp. 975-1048	
u	16.	Microchannel Plate (MCP), http://www.hpk.co.jp/eng/products/ETD/mcpe/mcpe.htm , 3/28/03, 2 pages	
u	17.	Microchannel Plate Principles of Operation, http://hea-www.harvard.edu/HRC/mcp/mcp.html , 3/28/03, 4 pages	
u	18.	Skala, Melissa, "Imaging X-Ray Fluorescence Using Microchannel Plate (MCP) Optics, Physics Department, Washington State University, Pullman, WA 99163, no date, 10 pages	
u	19.	A Well Collimated Quasi-Continuous Atom Laser, http://physics.nist.gov/Divisions/Div842/Gp4/AtomOptics/intro.html , 5/26/03, 2 pages	
u	20.	Module 1-4 Properties of Light, http://www.dewtronics.com/tutorials/lasers/leot/course01_mod04/mod01-04.html , 5/26/03, 32 pages	
u	21.	E. Hecht: "Optics" 1987, Addison-Wesley XP002184727, page 593-596	
u	22.	Anonymous: "Wafer Conformable Mask Image", Research Disclosure (December 1984) page 609 XP002184726.	
u	23.	C. Jacobsen et al; "Projection X-Ray Lithography Using Computer-Generated Holograms: A study of compatibility with proximity lithography"; Journal of Vacuum Science and Technology: Part B, Am Inst. of Physics. New York, US vol. 10. No. 6 (11/1/1992) pgs 3177-3181 XP000332529	
u	24.	C. Jacobsen et al; "X-Ray Holographic Microscopy Using Photoresists", Journal of the Optical Society of America - A, Optical Society of America, Wash. US. vol. 7, no 10 (10/1/1990) pgs 1847-1861 XP000163095.	
u	25.	Elliott, "Integrated Circuit Manufacturing Technology", pp 76-81 (1982)	
u	26.	Machine translation of Tetsuo et al., JP 11-329944	
u	27.	Machine translation of Tetsuo et al., JP 06-283585	
u	28.	J.C.H. Spence et al; <i>Low Energy Point Reflection Electron Microscopy</i> , Surface Review and Letters, Vol. 4, No. 3 (1997) pp 577-587	
u	29.	J.C.H. Spence et al; <i>On the reconstruction of low voltage point projection holograms</i> ; Electron Holography, (1995) pp 267-276	
u	30.	Hans-Werner Fink et al; <i>State of the Art Low-Energy Electron Holography</i> , Electron Holography (1995) pp 257-266	
u	31.	J.C.H. Spence et al; <i>Electron Holography at Low Energy</i> , Introduction to Electron Holography, pp 311-331	
u	32.	D.C. Joy et al; <i>Advanced SEM Imaging, Characterization and Metrology for ULSI Technology</i> ; 1998 International Conference, pp 653-666	
u	33.	Russell Young et al; <i>The Topografiner: An Instrument for Measuring Surface Microtopography</i> , Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011	
u	34.	G. Morton et al; <i>Point Projector Electron Microscope</i> , Phy. Rev. Vol. 56, 705 (1939)	

Examiner Signature		Date Considered	11/28/04
--------------------	---	-----------------	----------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.